



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**
Norio KIMURA et al. : Docket No. 2001-0660A
Serial No. 09/864,208 : Group Art Unit 1763
Filed May 25, 2001 : Examiner Sylvia MacArthur

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SUBSTRATE POLISHING APPARATUS AND
SUBSTRATE POLISHING METHOD

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a one month extension of time to respond to the communication of June 26, 2003.

The fee of \$110.00 is

- ☒ submitted herewith.
☐ to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.
☐ Small entity status of this application is established by a Small Entity Status Assertion which
☐ is enclosed.
☐ has been previously submitted.

Respectfully submitted,

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Norio KIMURA et al.

By

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October 6, 2003

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